

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 10/075,193
Filing Date February 13, 2002
Inventor Shenlin Chen et al.
Assignee Micron Technology, Inc.
Group Art Unit 2813
Examiner Huynh, Y.
Attorney's Docket No. M22-1927
Title: Methods of Forming a Capacitor Structure

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## SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References - See Attached Form PTO-1449

The Examiner's attention is directed to the references which are listed on the attached Form PTO-1449, copies of which are attached. No admission is made regarding whether all the submitted references are prior art.

Citation of the referenced art is respectfully requested.

This Supplemental Information Disclosure Statement is being filed within three months of the filing date of the application or before the mailing date of a first Office Action, whichever occurs last. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. § 1.17(p) to Deposit Account No. 23-0925.

Respectfully submitted,

Dated:

Bv:

ennifer J. Taylor, Ph.D.

Reg. No. 48,711